DOCKET NO: 259211US2X PCT

## IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

KENICHI HAMA, ET AL. : ATTN: APPLICATION DIVISION

SERIAL NO: NEW U.S. PCT APPLICATION

(BASED ON PCT/JP03/04530)

FILED: HEREWITH

FOR: PLASMA CVD FILM FORMING

APPARATUS AND METHOD FOR MANUFACTURING CVD FILM COATING PLASTIC CONTAINER

## PRELIMINARY AMENDMENT

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

Prior to a first examination on the merits, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 12 of this paper.

Remarks/Arguments begin on page 22 of this paper.